

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: C. Saloma et al.

Serial No. : Not Yet Assigned

For: METHOD FOR GENERATING HIGH-CONTRAST  
IMAGES OF SEMICONDUCTOR SITES VIA ONE-  
PHOTON OPTICAL BEAM-INDUCED CURRENT  
IMAGING AND CONFOCAL REFLECTANCE  
MICROSCOPY

Filed: Herewith

Examiner: Not Yet Assigned

Art Unit: Not Yet Assigned

Confirmation No. : Not Yet Assigned

Customer No. : 27,623

Attorney Docket No.: 0002031USU/2280

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Dear Sir:

Prior to examination on the merits, please amend the above-identified application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** begin on page 4 of this paper.

**Amendments to the Abstract** begin on page 7 of this paper.

**Remarks** begin on page 8 of this paper.